

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the application of: ) **CONFIRMATION NO.: 1461**  
 )  
 **Yasuhiko KOJIMA, et al.** )  
 )  
 U.S. Serial No.: 10/591,476 ) Group Art Unit: 1792  
 )  
 Filed: September 1, 2006 ) Examiner: Mandy C. Louie

For: COPPER FILM DEPOSITION METHOD

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed June 16, 2009 is due by July 16, 2009. The Action required restriction between two patentably distinct inventions.

Applicants hereby elect without traverse Group I of claims 1-14 and 17-24, drawn to a film deposition method by vapor deposition, for examination in this application. Applicants advise that no change in the inventorship of the application will be required by the eventual cancellation of non-elected claims.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course.

It is submitted that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,

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